

U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)				Docket No. AMAT/2966.C1/DSM /BCVD/JW	Serial No. 10/684,079
INFORMATION DISCLOSURE STATEMENT BY APPLICANT O I P E				Applicant Bencher, et al.	Confirmation No. Unknown
(Use several sheets if necessary) JAN 26 2004 Examiner Unknown				Filing Date October 9, 2003	Group Unknown

U.S. Patent Documents

*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
VY	A1	6,528,426	03/04/2003	Olsen, et al.	438	689	10/15/1999
VY	A2	6,514,667	02/04/2003	Angelopoulos, et al.	430	271.1	08/17/2001
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*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
VY	B1	0 725 440	08/07/1996	EP	H01L	23/532	<input type="checkbox"/>	<input checked="" type="checkbox"/>
VY	B2	0 613 178	02/22/1994	EP	H01L	21/90	<input type="checkbox"/>	<input checked="" type="checkbox"/>
VY	B3	99/33102	07/01/1998	WO	H01L	21/767	<input type="checkbox"/>	<input checked="" type="checkbox"/>

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VY	C1	Written Opinion from PCT/US99/22424, Dated April 5, 2001.	
VY	C2	PCT International Search Report for PCT/US99/22425, Dated February 2, 2000.	

Examiner *VY* Date Considered *04/29/05*

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↑	A18	5,789,316	08/04/1998	Lu	438	638	03/10/1997
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V. Y.	C4	Dijkstra, et al., "Optimization of Anti-Reflection Layers for Deep UV Lithography", Proceedings of SPIE Optical Laser Microlithography, Bellingham, SPIE, Vol. 1927, pages 275-286.				
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V. Y.	C6	PCT International Search Report for PCT/US99/22317, Dated March 21, 2000.				
Examiner	V. Y. Bencher					Date Considered 04/12/9105
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.						

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